

Title: APPARATUS AND METHOD FOR CLEANING AT LEAST ONE PROCESS CHAMBER FOR COATING
AT LEAST ONE SUBSTRATE

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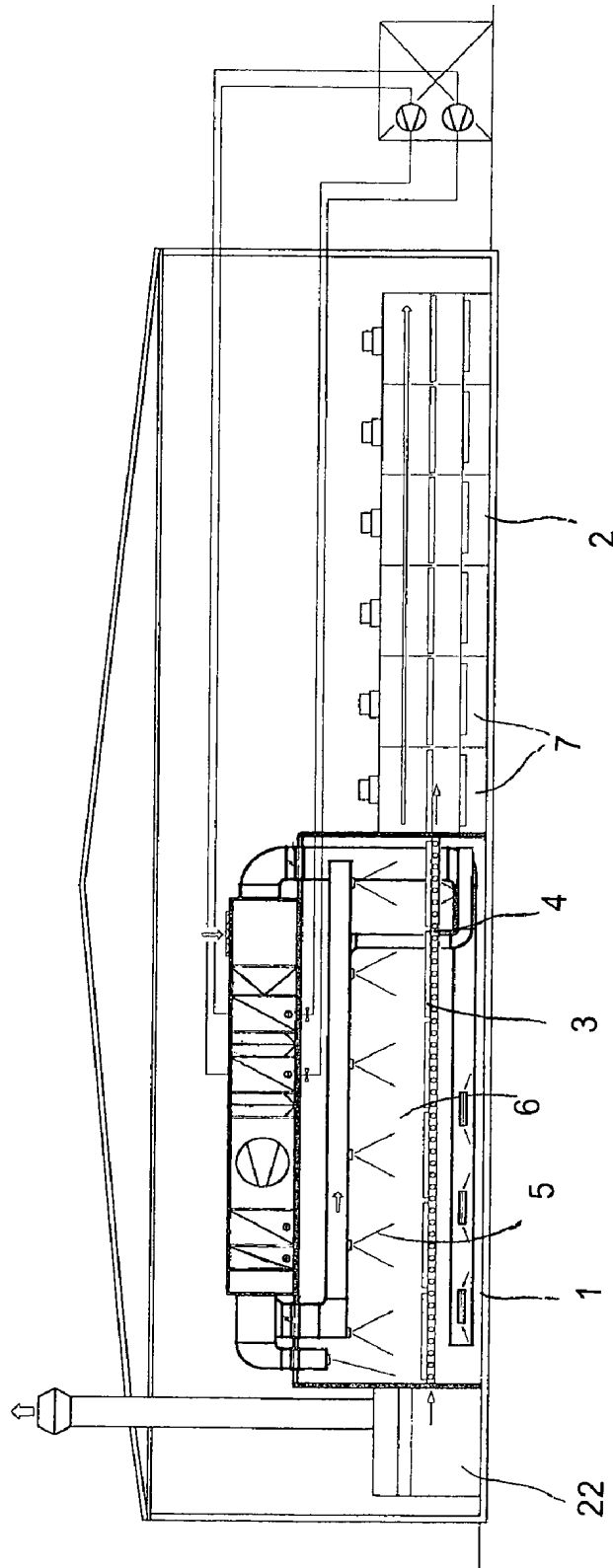


FIG 1

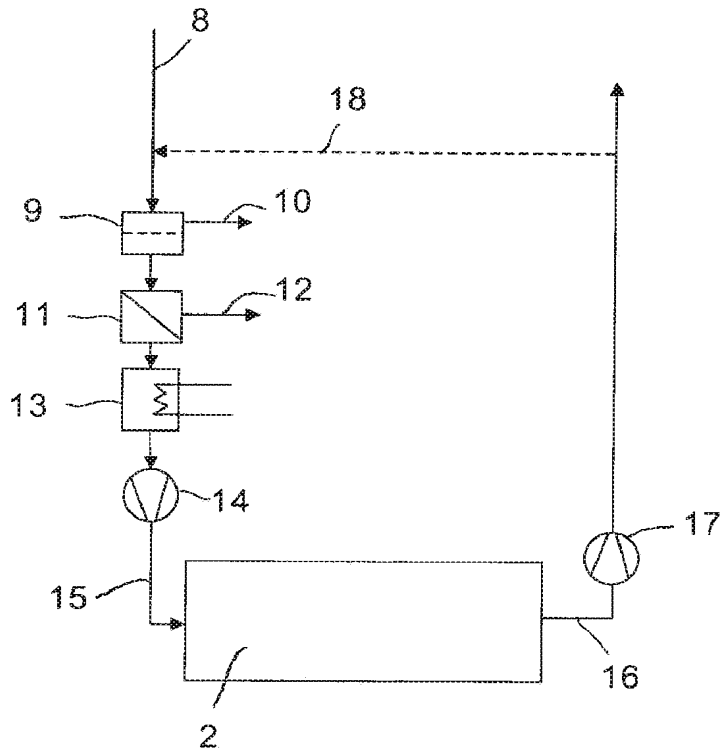


FIG 2

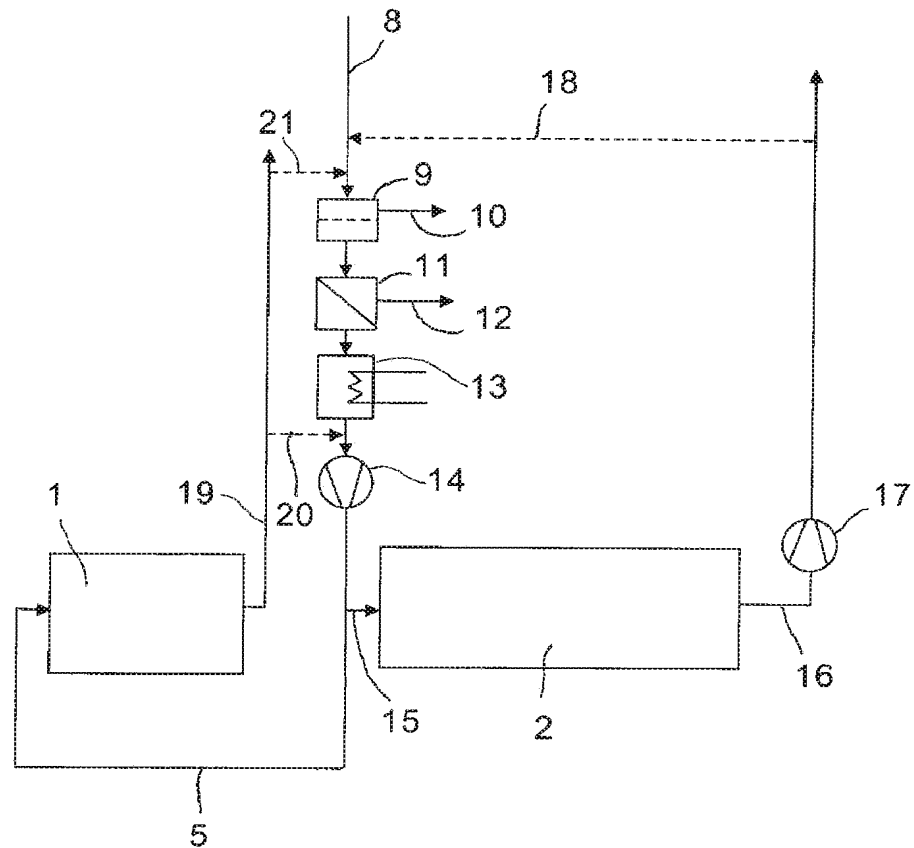


FIG 3

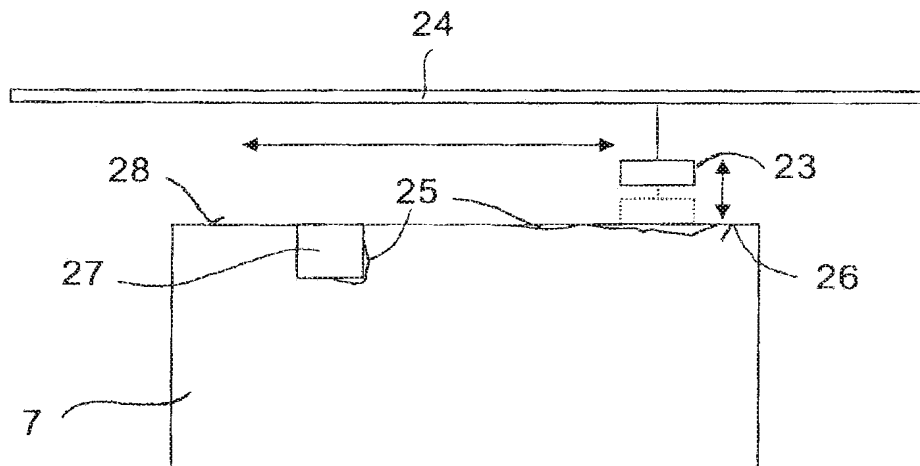


FIG 4